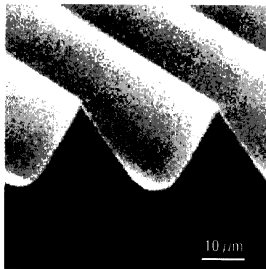


# ULTRASHARP

CANTILEVERS & GRATINGS

## TGG01

[ test structure ]

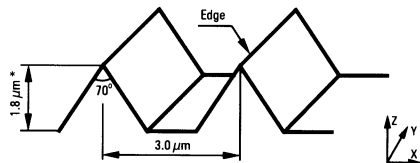


SEM image of the silicon grating TGG01.

### Grating Characteristics:

Active area .....	<b>3x3 mm</b>
Radius of curvature of a pillar edge .....	<b>less than 10 nm</b>
Pitch .....	<b>3 μm</b>

## TGG01



The dimensions marked \* are given for information only .

Silicon calibration gratings of TGG series have precise linear and angular dimensions of the stripes, formed by  $\langle 111 \rangle$  silicon crystallographic planes. It is characterized by small curvature radius of the edges (less than 10 nm) over the whole sample area. The pitch is 3 μm. The gratings are used for lateral calibration of SPM scanners, correction of vertical non-linearities, assessment of angular distortions, and characterization of cantilever tips.